



EHS NA TC Chapter Meeting Summary and Minutes

NA Fall Standards Meetings

Thursday, November 9, 2017

9:00 AM – 5:00 PM

SEMI HQ, Milpitas, California

TC Chapter Announcements

Next TC Chapter Meeting

Thursday, April 12, 2018 Milpitas, CA in conjunction with the NA Spring Standards Meeting 2018. Check www.semi.org/en/standards for the latest update.

Table 1 Meeting Attendees

Co-Chairs: Chris Evanston (Salus Engineering International), Sean Larsen (Lam Research), Bert Planting (ASML)

SEMI Staff: Kevin Nguyen (SEMI HQ)

<i>Company</i>	<i>Last</i>	<i>First</i>	<i>Company</i>	<i>Last</i>	<i>First</i>
Lam Research	Claes	Brian	SCREEN	Nishimura	Takayuki
Tokyo Electron	Clifton	Brick	ASML	Planting	Bert
<i>Tokyo Electron</i>	<i>Crane</i>	<i>Lauren</i>	<i>TUV SUD</i>	<i>Prasad</i>	<i>Ron</i>
Salus Engineering	Evanston	Chris	Tokyo Electron	Rivera	Kalysha
ASM	Fessler	Mark	<i>Texas Instruments</i>	<i>Schwab</i>	<i>Paul</i>
Nikon Precision	Greenberg	Cliff	Safety Guru	Sklar	Eric
Applied Materials	Karl	Ed	<i>MURATA MACHINERY</i>	<i>Tominaga</i>	<i>Tadamasa</i>
Lam Research	Larsen	Sean	Tokyo Electron	Tsuru	Mark
Tokyo Electron	Mashiro	Supika	<i>Intel</i>	<i>Wallace</i>	<i>Casey</i>
KLA-Tencor	McDaid	Raymond			

Italic indicates remote participant

Table 2 Leadership Changes

<i>WG/TF/SC/TC Name</i>	<i>Previous Leader</i>	<i>New Leader</i>
S3 Revision TF	Mark Fessler (ASM)	Glenn Hobrook (ASM)

Table 3 Committee Structure Changes

<i>Previous WG/TF/SC Name</i>	<i>New WG/TF/SC Name or Status Change</i>
None	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
5761B	New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes	Failed and returned to TF for rebalot
6204	Line Item Revisions to SEMI S6-0707E With Title Change To: Environmental, Health, and Safety Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment	

Table 4 Ballot Results

<i>Document #</i>	<i>Document Title</i>	<i>Committee Action</i>
	Line Item 1 - Changes to Appendix 1	Passed as balloted
	Line Item 2 - Add Table of Contents and remove list of sections from scope section	Passed with editorial changes
	Line Item 3 - Update retroactive clause to refer to more versions than S6-93 and align with S2 revision	Passed with technical changes. Ratification Ballot will be issued.
	Line Item 4 - Clean up some references to other documents	Passed as balloted

#1 **Passed** ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

#2 **Failed** ballots and line items were returned to the originating task forces for re-work and re-balloting or abandoning.

Table 5 Activities Approved by the GCS between meetings of the TC Chapter

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
None			

Table 6 Authorized Activities

<i>#</i>	<i>Type</i>	<i>SC/TF/WG</i>	<i>Details</i>
6309	SNARF	Ergonomics TF	Line Item Revision to S8-0915, Safety Guideline for Ergonomics Engineering of Semiconductor Manufacturing Equipment
6310	SNARF	S28 Revision TF	Reapproval of SEMI S28-1011, Safety Guideline for Robots and Load Ports Intended for Use in Semiconductor Manufacturing Equipment

#1 SNARFs and TFOFs are available for review on the SEMI web site at: <http://downloads.semi.org/web/wstdsbal.nsf/tfofsnarf>

Table 7 Authorized Ballots

<i>#</i>	<i>When</i>	<i>SC/TF/WG</i>	<i>Details</i>
R6204	Cycle 9-17	S6 Revision TF	Ratification Ballot - Line Item Revision to SEMI S6-0707E Environmental, Health, and Safety Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment
5761C	Cycle 1 or 2 -18	Energetic Materials TF	New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes
5969A	Cycle 1 or 2 -18	Fire Protection TF	Line Item Revisions to SEMI S2, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (pertaining to fire)
6309	Cycle 1 or 2 -18	Ergonomics TF	Line Item Revision to S8-0915, Safety Guideline for Ergonomics Engineering of Semiconductor Manufacturing Equipment
6310	Cycle 9-17, 1 or 2 -18	S28 Revision TF	Reapproval of SEMI S28-1011, Safety Guideline for Robots and Load Ports Intended for Use in Semiconductor Manufacturing Equipment



Table 8 SNARF(s) Granted a One-Year Extension

#	TF	Title	Expiration Date
None			

Table 9 SNARF(s) Abolished

#	TF	Title
None		

Table 10 Standard(s) to receive Inactive Status

Standard Designation	Title
None	

Table 11 New Action Items

Item #	Assigned to	Details
Nov092017-#1	Kevin Nguyen (SEMI Staff)	To work with Sean Larsen and Glenn Holbrook for the S6 Ratification Ballot.
Nov092017-#2	Sean Larsen (Lam Research)	To send contact of Alex McEachern to Mark Fessler
Nov092017-#3	All TF leaders	TF has upcoming teleconferences, please send meeting information to Eric Sklar.

Table 12 Previous Meeting Action Items

Item #	Assigned to	Details	Status
July132017-#1	Kevin Nguyen (SEMI Staff)	To ensure doc. 6124, Revision to SEMI E95-1101, Specification for Human Interface for Semiconductor Manufacturing Equipment, intercommittee ballot to EHS Committee	Completed
July132017-#2	Lauren Crane	To distribute slides from ICRC meeting to its members	Completed
July132017-#3	Kevin Nguyen (SEMI Staff)	To check with SEMI IT for an email distribution list for EHS meetings Google calendar.	Completed. SEMI IT will look into it.

1 Welcome, Reminders, and Introductions

Bert Planting called the meeting to order at 9:00 AM. The meeting reminders on antitrust issues, intellectual property issues and holding meetings with international attendance were reviewed. Attendees introduced themselves.

2 Review of Previous Meeting Minutes

The TC Chapter reviewed the minutes of the previous meeting.

- Motion:** Accept the minutes as written
- By / 2nd:** Cliff Greenberg/Mark Fessler
- Discussion:** None
- Vote:** 6-0. Motion passed



3 Ballot Review

Passed ballots and line items will be submitted to the ISC Audit & Review Subcommittee for procedural review.

Failed ballots and line items were returned to the originating task forces for re-work and re-balloting.

NOTE 1: TC Chapter adjudication on ballots reviewed is detailed in the Audits & Review (A&R) Subcommittee Forms for procedural review. The A&R forms are available as attachments to these minutes. The attachment number for each balloted document is provided under each ballot review section below.

3.1 *Doc. 5761B, New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes*

Motion: To find negative on LMRC42 is related and technically persuasive

By / 2nd: Sean Larsen /Mark Fessler

Discussion: None

Vote: 7-2. Motion passed

3.1.1 Doc. 5761B failed technical review. See attachment for the listing of all negatives.

Attachment: **5761B_CompiledResponses_tf08nov17b**

3.2 *Doc. 6204, Line Item Revisions to SEMI S6-0707E With Title Change To: Environmental, Health, and Safety Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment*

3.2.1 *Line Item 1 - Title change to align with procedure manual*

3.2.1.1 It passed as balloted.

3.2.2 *Line Item 2 - Add Table of Contents and remove list of sections from scope section*

3.2.2.1 It passed with editorial changes.

3.2.3 *Line Item 3 - Update retroactive clause to refer to more versions than S6-93 and align with S2 revision*

3.2.3.1 It passed with technical changes. Ratification Ballot will be issued in cycle 9-2017.

3.2.3.2 **Action Item # 1** – Kevin Nguyen to work with Sean Larsen and Glenn Holbrook for the Ratification Ballot.

3.2.4 *Line Item 4 - Clean up some references to other documents*

3.2.4.1 It passed as balloted.

Attachment: **6204 Procedural Review**

3.3 Publication Improvement Proposal (PIP) form was submitted for SEMI S6-0707E, Environmental, Health, and Safety Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment. The correction was to fix an error made on the original ballot. See attachment for details.

Attachment: **PIPForm - S6 RI Unit Conversion**

4 Liaison Reports

4.1 *Japan TC Chapter*

4.1.1 Supika Mashiro reported. Of notes:

- Last Meeting



- 10:00-17:30, October 4, 2017
at SEMI Japan, Tokyo, Japan
- Next Meeting
 - 13:00-16:00, Friday, December 15, 2017
at Conference Tower, Tokyo Big Sight, Tokyo, Japan
- Standard to receive Inactive Status
 - SEMI S16-0307 (Reapproved 0812):
 - Guide For Semiconductor Manufacturing Equipment Design For Reduction Of Environmental Impact At End Of Life
 - SEMI S24-0306 (Reapproved 0811):
 - Safety Guideline For Multi-Employer Work Areas
 - SEMI S29-0712:
 - Guide For Fluorinated Greenhouse Gas (F-GHG) Emission Characterization And Reduction
- STEP Planning Working Group
 - STEP/SEMI S23 was held on September 29, 2017, with about 30 participants. Webinar will be considered.
 - STEP/SEMI S2 was held on October 20, 2017, with about 60 participants.
 - Discussions:
 - Mark Fessler: who created slides for these STEPS?
 - Supika Mashiro responded: Equipment suppliers, 3rd party evaluators, and veteran committee members. Committee co-chairs also oversee and review to ensure materials are aligned with the latest version of published SEMI Safety Guidelines.
 - Chris Evanston: Japan has done a great job, however, other regions are not so.
 - Eric Sklar: The quality of presentation materials from other regions is less desirable.

Attachment: EHS Japan_NA_20170626

4.2 Taiwan TC Chapter

4.2.1 Kevin Nguyen reported. Of notes:

- Last Meeting
 - October 15, 2017
SEMI Taiwan office, Hsinchu, Taiwan
- Next Meeting
 - March 21, 2018
SEMI Taiwan office, Hsinchu, Taiwan
- Environmental Sustainability TF was disbanded
- Equipment Safety TF
 - Discussions:
 - Safety Guidelines for
 - Feasibility for the standard of movable robot in combining S17 with S28.
 - Battery use in movable robot operating in clean room.
 - Moveable robot for earthquake



- energy saving for clean room
 - For energy saving, the ventilation design in clean room should consider appropriate ventilation within a safe range.
 - The suggested guidelines in S2 and S23 are too wide to waste electrical power.
- Seismic TF
 - Will plan to work with JP Seismic Protection TF to discuss about equipment of seismic protection issue.

Attachment: Taiwan EHS Liaison Report _ 20171102 rev1

5 Subcommittee & Task Force Reports

5.1 Manufacturing Equipment Safety Subcommittee (MESSC)

5.1.1 Cliff Greenberg reported. Of notes:

- MESSC still needs another co-chair: any volunteers?
- Single fault failures in S2
- “Should” means “Shall?”
 - Non-consistent wording, and Notes or Notices that attempt to say the same thing throughout “S” documents. MESSC recommends that Committee ask Staff to identify the inconsistencies and propose consistent wording
 - Discussions:
 - A consistent Notice should be crafted for SEMI staff to apply for all SEMI Safety Guidelines.
 - Eric Sklar said a thorough review is needed to see how each note or notice is used in each of these Safety Guidelines. Further review is needed before a decision can be made.
 - This issue will need to be discussed again at the next meeting in Spring 2018.
- From ICRC: S2 and Machinery Directive alignment
 - No MESSC objections to a proto-TF and TFOF to start work on AUX031 and alignment issues if sufficient interest develops for participation

Attachment: MESSC Fall 2017 minutes

5.2 S10 Revision TF

5.2.1 Bert Planting reported the TF discussed changes to severity group from line item 1 of ballot 6049, which previously failed at SEMICON West. The proposed changes (people, equipment, facility and environment) generated more discussions. Evidently, consensus is far from reaching.

5.2.2 Discussions:

- Raymond McDaid: There was no third party evaluator presence in the TF meeting to get the opinion from their side. As presented, the whole tool can be thrashed if there is no human injury involved?
- Chris Evanston: What is the motivation for changing as proposed? He believes the issue was discussed a long time ago, and thinks we are trying to fix something that is not broken.
- Bert Planting responded: The change would provide further clarification on the severity group.
- Mark Fessler: For equipment suppliers, their concern is equipment reliability.



- Lauren Crane: One can have a significant damage, but it would ok as long as there is no injury to human?
- Eric Sklar: For the end user, there is loss of productivity if equipment is damage. They would want to get equipment supplier to fix it.

5.2.3 Bert Planting said the TF will continue to have teleconferences after the holiday season to resume discussion and prepare a proposal for the Spring meeting.

Attachment: SEMI S10 Fall 2017_bp07nov17a_es09nov17B

5.3 Fire Protection TF

5.3.1 Eric Sklar reported. Of notes.

- Results of Line Item Ballot:
 - SEMI Draft Document #6172: Line Item Revision to SEMI S14-1016: Safety Guidelines for Fire Risk Assessment and Mitigation for Semiconductor Manufacturing Equipment (To correct nonconforming title)
A&R rejected the EHS Committee's finding of the one Negative to be RNP, therefore ballot has failed. Neither the TF nor its leaders is inclined to spend further time and effort on this.
- Previous Ballot:
 - Doc. #5969: Addition of criteria to determine which method of assessing fire risk is to be used. Failed, returned to TF for rework and rebalot. TF plans to rebalot before Spring Meetings.
- Other Topics
 - Continue work on S14 topics

Attachment: FPTF_tf08nov17a

5.4 S3 Revision TF

5.4.1 Eric Sklar reported. Of notes.

- TF has been discussing scoping, currently intended to be:
 - Heating of chemicals obtained as solids, liquids, gases, or combinations thereof
 - Chemicals used as liquids, gases, or combinations thereof
 - Chemicals used directly for processing and for such purposes as in situ chamber cleaning and seasoning
 - Heating to maintain the temperature of piping and other components to manage the risks resulting from condensation
 - Heating upstream of, and downstream of process chambers.
 - Other improvements that might be found appropriate for EHS Committee consideration
- Other Topics
 - TF Leadership: Mark Fessler (ASMI) stepped down, suggesting that Glenn Holbrook (ASMI) replace him.

Motion: To approve Glenn Holbrook (ASMI) as a new leader

By / 2nd: Eric Sklar/Mark Fessler

Discussion: None

Vote: 9/0. Motion passed

Attachment: S3rev_tf08nov17a



5.5 S2 Chemical Exposure TF

5.5.1 Sean Larsen reported S2 revisions are ongoing. Discussions are taking place.

5.6 S22 TF

5.6.1 Chris Evanston reported good discussions are progressing for alignment of S2 with SEMI S22.

5.7 S28 Robots & Loadports TF

5.7.1 Chris Evanston reported it is not a good idea to expand the scope of S28. Therefore, he proposed sending S28 for reapproval ballot.

5.8 Control of Hazardous Energy (CoHE) TF

5.8.1 Mark Fessler reported progress of the TF. Of notes;

- CoHE White Paper (14 pages) was finally Published on SEMI Website at!
 - <http://www.semi.org/en/semi-2016-white-paper-cohe-loto>
- Current activity
 - SEMI Draft Document #5957 (Line Item Revision of S2, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment. (Re: Control of Hazardous Energy)) draft rewrite of SEMI S2 Section 17
 - We will continue to work on draft for further discussion in Spring Meetings (March/April 2018)

Attachment: **CoHE_Task Force Report Nov 2017**

5.9 S2 Anchorage TF

5.9.1 Raymond McDaid reported the TF had one teleconference. There was no issue with the proposal. SNARF has not been submitted, so there is no document number. The TF plans to issue a SNARF and ballot for review at NA Spring meetings, pending authorization of the GCS.

5.10 S8 (Ergonomics) TF

5.10.1 Paul Schwab reported the TF requested (At West) an additions to SNARF # 5996 Improvements to SEMI-S8 Appendix 1 SESC:

- Product loading criteria for non-wafers cassettes, including single reticle containers (request from Shanghai Microelectronics Equip.)

5.10.2 Also, a new SNARF is proposed to improve S8 based on the results of Ratification Ballot R5917.

Motion: To approve SNARF for line item changes to S8

By / 2nd: Sean Larsen/Cliff Greenberg

Discussion: [Supika Mashiro] Will this activity be overlapped with SNARF 5996?. [Paul Schwab] No.

A change was made to the scope section to clarify that this is independent of #5996.

Vote: 3/0. Motion passed



Attachment: SEMI_S8_SNARF_req_08NOV2017

Attachment: SEMI-S8_TF_meeting_summary_09NOV2017 (1)

5.11 S2 Seismic Protection Liaison TF

5.11.1 Lauren Crane reported TF progress:

- 2 change proposals for changes to DR information in S2 (scheduled to ‘move’ in July 2018) were sent following ‘West to main JP task force, 2 more were under development
- Continued working on last item (‘negligible force’ issue), made some progress, will call telecon’s to complete. Targeting completion prior to Spring meetings.
- Hoping timing will work so that Japan TF can put out ballot to modify DR before July 2018.
- Discussion - official version of S2 with implementation of delayed revision will be kicked on July 2018. Supika Mashiro recommended the TF to consider timing for ballot and TC Chapter adjudication, so it would get implemented by July.

Attachment: S2 NA Seismic LTF ftf mtg 7Nov2017 r1

5.12 Other TC documents of interest

5.12.1 Sean Larsen mentioned Power Harmonic TF from the Facilities committee, led by Alex McEachern, is trying to address harmonic issue. Distorted (harmonic) voltages and distorted (harmonic) currents are an increasingly urgent problem for tool vendors and fabs. There is no standardized way for the tool vendors and the fabs to even communicate about their requirements.

Discussion: [Mark Fessler] Who is leading this activity? **Action Item # 2:** Sean Larsen will provide Alex’s email to Mark.

5.12.2 Supika Mashiro mentioned there is a potential activity on rested mode, integrated by equipment supplier for revision of SEMI E167-1213 - Specification for Equipment Energy Saving Mode Communications (EESM). This activity, led by Europe, was discussed in the I&C TC Chapter, and it may contradict with SEMI S23-1216 Guide for Conservation of Energy, Utilities and Materials Used by Semiconductor Manufacturing Equipment.

6 Leadership & Liaison Reports

6.1 ICRC Liaison

6.1.1 Lauren Crane reported on the ICRC. Of notes,

- ICRC NA-C Invited to GPERA (Global Product EHS Regulatory Advocacy [Special Interest Group]) discussion meetings at end of September.
- Main slides including agenda (presentations not embedded in this deck will be distributed with meeting notes)
- Highlights from Monday’s meeting
 - Interest, but no significant concerns with possible GPERA impact on ICRC.
 - Strong agreement on philosophy of a global ICRC with two regional chapters.
 - Significant interest in findings of EU’s Machinery Directive revision preparatory study report Request to bring discussion of possible AUX031 MD/S2 alignment TF to MESSC for discussion – Done
 - Top 5 regulatory concerns from the meeting



- PFOA in supply chain
- Stockholm Convention - PFOA
- EU Once and article always an article (OA5)
- Korea EASCA
- EU RoHS Recas

6.1.2 Sanjay Baliga also reported Fab Owners Association (FOA) recently join SEMI as strategic association partner. There is a plan to have an EHS event at SEMICON West 2018, so he advises all stakeholders including ICRC, EHS members, and FOA to coordinate with scheduling to minimize schedule conflict.

Attachment: SEMI Fall 2017 stnds ICRC and Seismic LTF reports L.Crane r1

6.1.3 RSC / Committee Leadership Report

6.1.3.1 Sean Larsen reported. Of notes.

- *Korean translation of S2*
 - Old version of S2 is translated.
- *Virtual Meetings Status*
 - Progress is made, but it is not ready.
 - For large crowd, it may not be productive especially microphone issue. Also, noise interference is an issue, for example, the fan noise in the meeting rooms at the SF Marriott is loud.
- *Regulations*
 - It is still unclear on what is allowed and not allowed for editorial changes for reapproval ballot.

7 SEMI Staff Report

7.1.1 Kevin Nguyen (SEMI) gave the SEMI Staff Report. Of note:

- Next meetings
 - April 9-12, 2018
 - SEMI HQ in Milpitas, California
- 2017 Critical Dates for SEMI Standards Ballots
 - Cycle 9, 2017
 - Ballot Submission Date: Nov 16
 - Voting Period Starts: Nov 29
 - Voting Period Ends: Dec 29
- 2018 Critical Dates for SEMI Standards Ballots
 - Cycle 1-4 are determined
 - Cycle 5-9 will be determined in December or January 2018.
 - Check website for latest info.
 - <http://www.semi.org/en/Standards/Ballots>
- SEMI Standards Publications
 - Total SEMI Standards in portfolio: 978
 - Includes 210 Inactive Standards

Attachment: Staff Report Nov 2017 v2



8 Old Business

8.1 SNARF Extensions (older than 3 years)

8.1.1 All is up to date.

9 New Business

9.1 Upcoming Ballot Authorizations

R6204	Cycle 9-17	Ratification Ballot - Line Item Revisions to SEMI S6-0707E Environmental, Health, and Safety Guideline for Exhaust Ventilation of Semiconductor Manufacturing Equipment
5761C	Cycle 1 or 2 - 18	New Standard: Safety Guideline for Use of Energetic Materials in Semiconductor R&D and Manufacturing Processes
5969A	Cycle 1 or 2 - 18	Line Item Revisions to SEMI S2, Environmental, Health, and Safety Guideline for Semiconductor Manufacturing Equipment (pertaining to Fire)
6309	Cycle 1 or 2 - 18	Line Item Revision to SEMI S8-0915, Safety Guideline for Ergonomics Engineering of Semiconductor Manufacturing Equipment
6310	Cycle 9-17	Reapproval of SEMI S28-1011, Safety Guideline for Robots and Load Ports Intended for Use in Semiconductor Manufacturing Equipment

Motion: To authorize above documents for ballots

By / 2nd: Eric Sklar/Bert Planting

Discussion: None

Vote: 6/0. Motion passed

9.2 Teleconference Scheduling

9.2.1 **Action Item # 3:** If any TF has any upcoming teleconferences, please remember to copy Eric Sklar.

10 Next Meeting and Adjournment

10.1 The next meeting is scheduled for Thursday, April 12, 2018 at SEMI HQ in Milpitas, CA. See <http://www.semi.org/en/events> for the current list of meeting schedules.

Having no further business, a motion was made to adjourn. Adjournment was at 12:30 PM.

Respectfully submitted by:

Kevin Nguyen,
SEMI Standards Operations Manager
Phone: 408-943-7997
Email: knguyen@semi.org

Minutes tentatively approved by:

Sean Larsen (Lam Research)	<Date approved>
Chris Evanston (Salus Engineering International)	<Date approved>
Bert Planting (ASML)	<Date approved>



Table 13 Index of Available Attachments#1

<i>Title</i>	<i>Title</i>
5761B_CompiledResponses_tf08nov17b	S3rev_tf08nov17a
6204 Procedural Review	CoHE_Task Force Report Nov 2017
PIPForm - S6 RI Unit Conversion	SEMI_S8_SNARF_req_08NOV2017
EHS Japan_NA_20170626	SEMI-S8_TF_meeting_summary_09NOV2017 (1)
Taiwan EHS Liaison Report__20171102 rev1	S2 NA Seismic LTF ftf mtg 7Nov2017 r1
MESSC Fall 2017 minutes	SEMI Fall 2017 stnds ICRC and Seismic LTF reports L.Crane r1
FPTF_tf08nov17a	Staff Report Nov 2017 v2
SEMI S10 Fall 2017_bp07nov17a_es09nov17B	

#1 Due to file size and delivery issues, attachments must be downloaded separately. A .zip file containing all attachments for these minutes is available at www.semi.org. For additional information or to obtain individual attachments, please contact [SEMI Staff Name] at the contact information above.